

# PROCEEDINGS OF SPIE

## ***Optical Metrology and Inspection for Industrial Applications XI***

**Sen Han  
Gerd Ehret  
Benyong Chen**

*Editors*

**12–14 October 2024  
Nantong, China**

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SPIE

**Volume 13241**

Proceedings of SPIE 0277-786X, V. 13241

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Please use the following format to cite material from these proceedings:

Author(s), "Title of Paper," in *Optical Metrology and Inspection for Industrial Applications XI*, edited by Sen Han, Gerd Ehret, Benyong Chen, Proc. of SPIE 13241, Seven-digit Article CID Number (DD/MM/YYYY); (DOI URL).

ISSN: 0277-786X

ISSN: 1996-756X (electronic)

ISBN: 9781510682108

ISBN: 9781510682115 (electronic)

Published by

**SPIE**

P.O. Box 10, Bellingham, Washington 98227-0010 USA

Telephone +1 360 676 3290 (Pacific Time)

[SPIE.org](http://SPIE.org)

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